



Recent Advances in Magnetolectric Materials and Devices

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Message from the Guest Editors

Dear Colleagues,

Over the last several decades, the magnetolectric (ME) effect has advanced rapidly and significantly, attracting both research and industrial attention. ME materials have been created in bulk and thin film, including single-phase compounds and composites such as piezoelectric/magnetostrictive composites in layered, granular, or pillared form via strain-mediated contact. ME materials exhibit a wide range of successful device applications, including ME antennas, magnetic field sensors, and actuators, to mention a few, that are lightweight, tiny, and low power and are dramatically transforming our daily lives. Both potential and challenges abound from the perspective of ME materials and devices, and many unanswered questions remain. Accordingly, this Special Issue seeks to showcase research papers, and review articles that focus on (1) new design, fabrication, characterization of ME materials in either single phase or composite form; and (2) modeling and characterization of ME devices with various configurations.





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Message from the Editor-in-Chief

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